

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of  
Applicants : Zheng et al.  
Serial No. : 10/790,492  
Filed : March 1, 2004  
Title: : **ATOMIC LAYER DEPOSITION OF CAPACITOR DIELECTRIC**  
Docket No. : MIO 0082 N2/40509.292  
Examiner : Thomas, Toniae M.  
Art Unit : 2822  
Conf. No. : 9512

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

EFS Web Electronic Submission  
July 20, 2006

Sir or Madam:

**AMENDMENT**

This paper is being filed in response to the Office Action mailed April 20, 2006.

Reconsideration of the present application is respectfully requested in light of the amendments and remarks below, which include, in order of appearance, beginning on separate sheets:

- Amendments to the Claims; and
- Remarks.